Custom Semiconductor Reticle Handling Automation

The Reticle Handling System is a highly reliable mask automation platform, designed to pair up with a variety of process tools or perform inspection, sorting, and cleaning applications. This system is designed to comply with the highest of ISO Class-1 cleanliness standards. The integrated 6-axis robot and edge grip end effector can perform flip and reorientation of reticles from a variety of presentation methods: SMIF POD, Open Cassette, Acclimation Cassette, Blank Box, and Compact Box.

FEATURES

- 6"x6" reticle and pellicle support
- Flip and rotation reorientation
- 6-axis robot and edge grip end effector
- Cleanliness levels down to ISO Class-1
- CE, SEMI S2, and SEMI S8 compliant

PACKAGE SUPPORT

- SMIF POD
- Open Cassette
- Acclimation Cassette
- Blank Box
- Compact Box

Reticle Handling Applications

CORNING OEM METROLOGY TOOL AUTOMATION

Load/unload masks from Open Cassettes or SMIF PODs to OEM process tool (reticle flatness measurement tool).

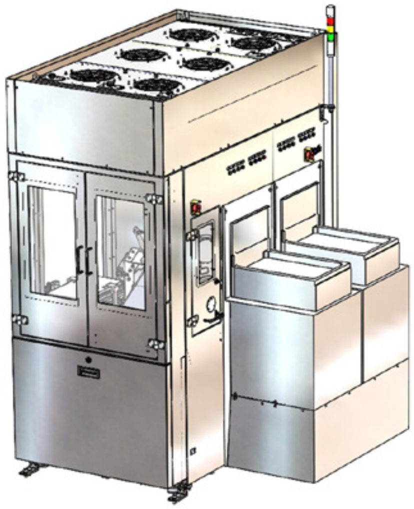
INTEL CLEANER AND SORTER

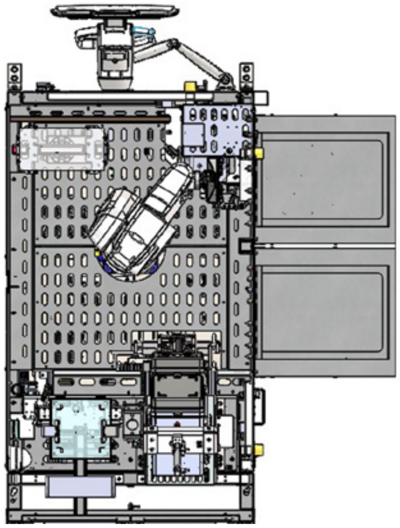
Load/unload masks from SMIF PODs to Intel cleaning chamber. Sort masks between SMIF PODs, compact boxes, and blank boxes.

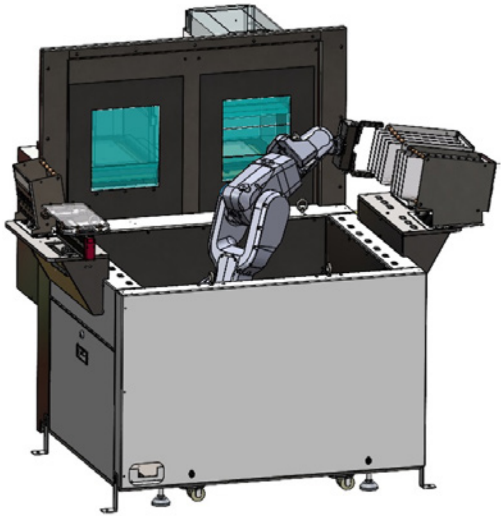
For additional information, visit jabil.com/precision-automation

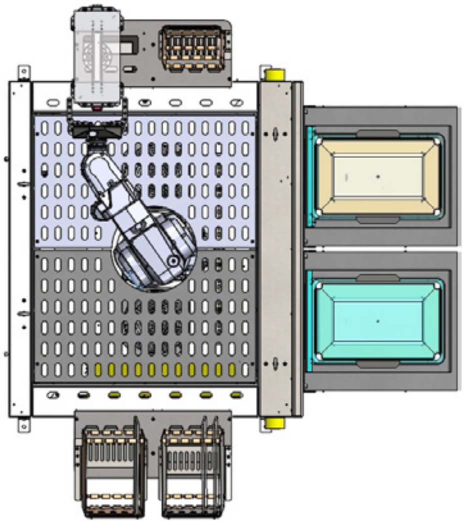
Large Format (6"X12" Next-Gen Mask Handling)

As the industry transitions from the current 6"x6" masks to the larger format 6"x12", Jabil is leading the development of next-generation automated reticle handling systems. Engineered for the demands of large format EUV and advanced lithography, our automaton solutions deliver unmatched precision, reliability, and throughput — enabling a seamless transition to the future of semiconductor manufacturing.









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